

INFORMATION DISCLOSURE STATEMENT

Applicant : Satoh *et al.*
App. No. : 10/759,953
Filed : January 16, 2004
For : SEMICONDUCTOR-PROCESSING
DEVICE PROVIDED WITH A
REMOTE PLASMA SOURCE FOR
SELF-CLEANING
Examiner : Jeffrie Robert Lund
Art Unit : 1792
Conf No. : 8185

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing
1 reference to be considered by the Examiner.

Please place this reference in the file of the above-identified patent application in
accordance with 37 C.F.R. § 1.97(i).

Respectfully submitted,
KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 8/17/09

By: 
Ian W. Gillies
Registration No. 62,280
Attorney of Record
Customer No. 20,995
(415) 954-4114